

# Electrochemical Behaviours of Two-Dimensional Materials

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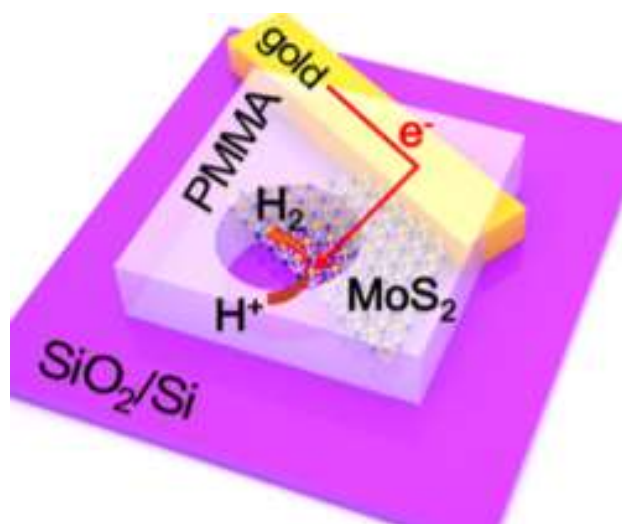
Abstract

In this talk, several aspects of the electrochemical behaviours of two-dimensional (2D) materials for energy applications will be discussed. First, large-area continuous few-layer molybdenum disulfide film is prepared by simple solid-gas elemental reaction and transferred onto fluorine doped tin oxide glass substrate as the counter electrode for dye-sensitized solar cells. The catalytic activities of the MoS<sub>2</sub> atomic layers are dramatically improved by carving the MoS<sub>2</sub> film and creating artificial edges on it [1]. Next, we developed a local probe electrochemical measurement method (Fig. 1) and successfully applied it to the electrocatalytic activity measurement of various kinds of transition metal dichalcogenides. The catalytic activity and turnover frequencies of the 2H-MoS<sub>2</sub> basal plane versus edge as well as the 1T'-MoS<sub>2</sub> basal plane are identified by this measurement [2]. At the same time, the basal plane activity and turnover frequencies of transition metal dichalcogenides from different element groups has been systematically studied. We have shown that the general trend of the transition metal dichalcogenides in the form of volcano plot follows the trend of metals. VB-VIA dichalcogenides have been identified as the preferred selection for non-noble metal hydrogen evolution reaction (HER) catalysts [3].

References

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- [2] J. Zhang, J. Wu, H. Guo, W. Chen, J. Yuan, U. Martinez, G. Gupta, A. Mohite, P.M Ajayan, J. Lou, *Advanced Materials*, 29(2017), 1701955.
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Figures



**Figure 1:** Schematic illustration of the on-chip local probe measurement setup [2]